

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	Group Art Unit: 2112
)	
Shinichiro Nohdo)	
)	Confirmation No.: 3173
Application No. 10/812,602)	
)	
Filed: March 30, 2004)	
)	
For: WAFER, EXPOSURE MASK, METHOD OF)	Examiner: Rebecca Slomski
DETECTING MARK AND METHOD OF)	
EXPOSURE)	

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO DECEMBER 11, 2006 OFFICE ACTION

Dear Sir:

This Amendment is submitted in response to the Office Action mailed December 11, 2006. Applicant respectfully requests amendment of the patent application, and reconsideration and allowance of the pending claims.